

Electron Beam Evaporation System

Model: SA-VKE550/E800

SA-VKE550 and SA-VKE800 are general-purpose electron-beam evaporation systems. Delivering high-performance, stable and reliable operation, they feature advanced automated control routines and low-maintenance design to fulfill versatile requirements for both mass production and experimental platforms.



Feature

- Low cost
- Lift-off
- Co-deposition
- High evaporation rate

Application

- Laser
- R&D
- Integrated circuit
- MEMS

Specifications:

Parameter	Descriptions
Number of Crucibles	8(max.)
Power Supply	10kW(max.)
Automatic Loadlocks	Single & multi-chip automatic loadlock
Film thickness monitoring	Crystal oscillator controller
Ion Source	RF & Kaufman & Hall ion source
Fixture types	Dome & Knudsen & Planetary & Plate
Pumping System	Cryopump / magnetically levitated turbo-molecular pump + Dry mechanical pump
Coating Uniformity	±3%
Coating Repeatability	±2%
Uniform Deposition Area	Ø300 mm(max.)
Ultimate Vacuum	1E-5Pa
Vacuum Measurement	Full-range vacuum gauge
Temperature Control Range	RT~300°C
Space Requirements(L×W×H,m)	3.35×2.8×2.2

Principle:

